

<b>Search Notes</b> 	<b>Application/Control No.</b> 10/813,194	<b>Applicant(s)/Patent under Reexamination</b> MINOURA, KIYOSHI
	<b>Examiner</b> Richard H. Kim	<b>Art Unit</b> 2871

INTERFERENCE SEARCHED			
Class	Subclass	Date	Examiner